

## Introduction

A typical application In the semiconductor industry is the handling of wafers. The wafer lift is an accessory which can be used with all magnetically driven dual shaft sample transporters. It allows for movement perpendicular to the transfer axis. The up/down movement is done with approximately half-turn in each direction of the outer magnet assembly of the sample transporter. Please contact us for a discussion about a customized interface for your specific wafer support.

Adds 2.0 to dimension Y of the main product

Description	Part Code
Wafer lifting device	M-FRKLIIFT

## Specifications:

### Materials

All UHV compatible

### Vacuum Range

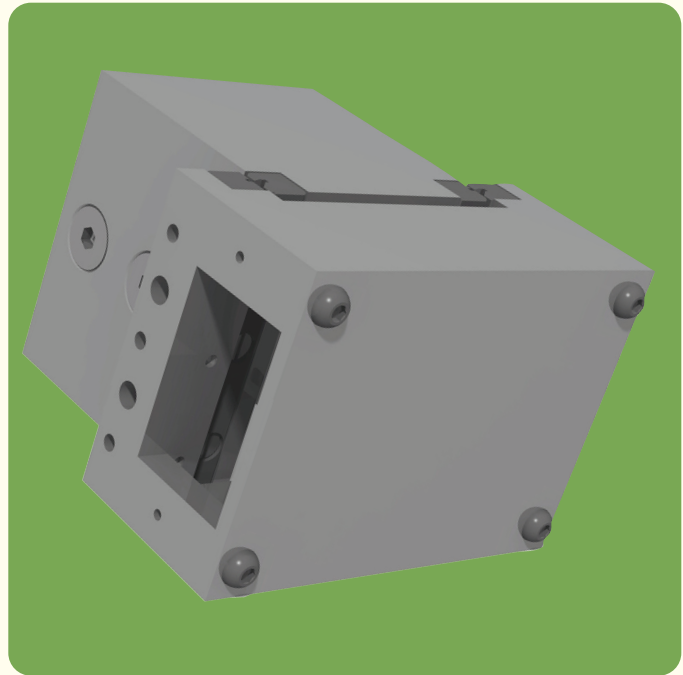
atm to  $1 \times 10^{-11}$  mbar

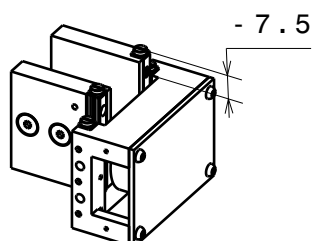
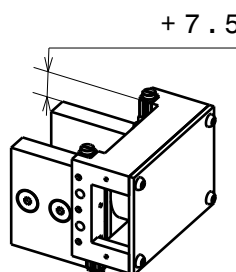
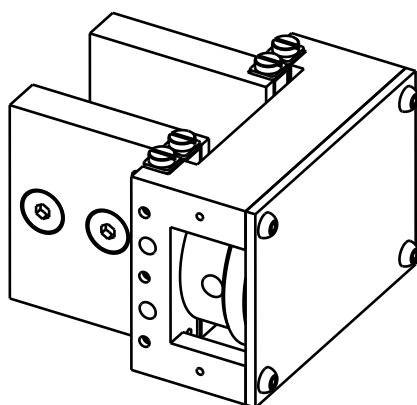
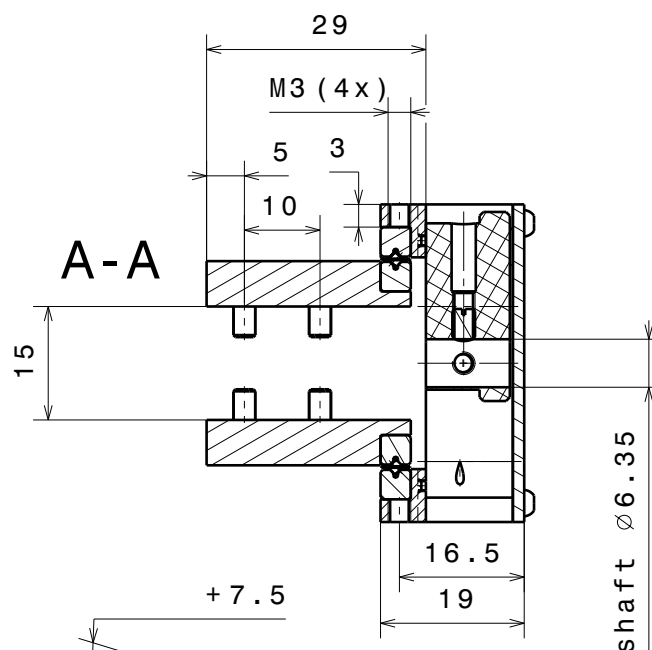
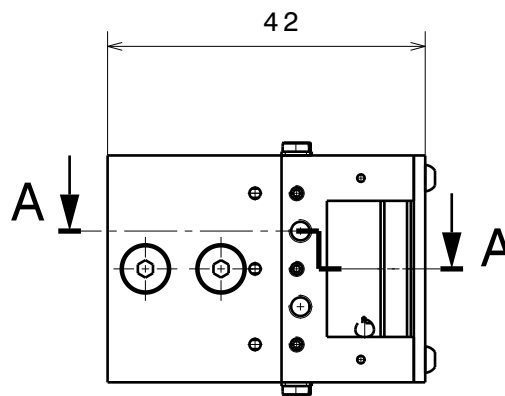
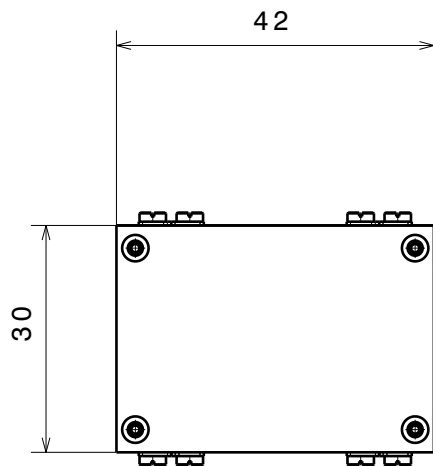
### Bakeout Temperature \*

200°C max.

### Lift / Travel

+/- 7.5mm





Material: all UHV compatible

Fork Lifter for RMD40(FL)

FRKLIFT

**Ferrovac GmbH**  
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nominal dimension	over up to	1	6	30	100	300	1000
tolerance	±	0.05	0.1	0.3	0.5	0.8	1.2

Scale	Drawn	A.Zandonella
	Date	18.09.2012
	Changed	24.09.18 JB

1:1

Rev. D

**FRKLIFT**

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